

TSMC-02-1147



February 18, 2004

To: Commissioner for Patents  
P.O.Box 1450  
Alexandria, VA 22313-1450

Fr: George O. Saile, Reg. No. 19,572  
28 Davis Avenue  
Poughkeepsie, N.Y. 12603

Subject: | Serial No. 10/719,721 11/21/03 |

Wen-Chi Chien

DYNAMICALLY ADJUSTING THE DISTRI-  
BUTION FOR DISPATCHING LOT BETWEEN  
CURRENT AND DOWNSTREAM TOOL BY USING  
EXPERTISE WEIGHTING MECHANISM

#### INFORMATION DISCLOSURE STATEMENT

Enclosed is Form PTO-1449, Information Disclosure Citation  
In An Application.

The following Patents and/or Publications are submitted to  
comply with the duty of disclosure under CFR 1.97-1.99 and  
37 CFR 1.56.

#### CERTIFICATE OF MAILING

I hereby certify that this correspondence is being  
deposited with the United States Postal Service as first class  
mail in an envelope addressed to: Commissioner for Patents,  
P.O. Box 1450, Alexandria, VA 22313-1450, on February 18, 2004.

Stephen B. Ackerman, Reg.# 37761

Signature/Date

"Understanding the Fundamentals of Kanban and Conwip Pull Systems Using Simulation," Marek, et al., Proceedings of the 2001 Winter Simulation Conference, pp. 921-929, found on website [www.informs-cs.org](http://www.informs-cs.org), 6/12/03. This paper presents an introductory overview and tutorial in simulation modeling and control of serial Kanban and CONWIP (CONstant Work In Process) pull systems using AREENA/SIMAN 3.5/4.0.

U.S. Patent 6,564,113 to Barto et al., "Lot Start Agent that Calculates Virtual Wip Time in a Multi-product and Multi-bottleneck Manufacturing Environment," describes a Lot start agent that calculates virtual WIP time in a multi-product and multi-bottleneck manufacturing environment.

U.S. Patent 6,470,227 to Rangachari et al., "Method and Apparatus for Automating a Microelectric Manufacturing Process," describes a method and the apparatus for automating a microelectric manufacturing process by configuring application objects that implement a domain knowledge for a piece of equipment and then implementing a workflow.

U.S. Patent 6,259,959 to Martin, "Method for Determining the Performance Components of a Manufacturing Line," describes a method for determining the performance components of a manufacturing line.

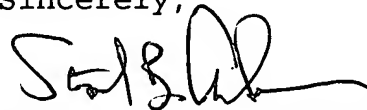
TSMC-02-1147

U.S. Patent 6,128,588 to Chacon, "Integrated Wafer FAB Time Standard (Machine Tact) Database," describes an integrated wafer fab time standard (machine tact) database.

U.S. Patent 5,826,238 to Chen et al., "Daily Target Generation and Machine Allocation with Priority," describes a method and system that operates a data processing system.

U.S. Patent 5,768,133 to Chen et al., "WIP/Move Management Tool for Semiconductor Manufacturing Plant and Method of Operation Thereof," describes a WIP/move management tool for semiconductor manufacturing plant and method of operation thereof.

Sincerely,

A handwritten signature in black ink, appearing to read "S. B. Ackerman", written over a horizontal line.

Stephen B. Ackerman,  
Reg. No. 37761

Form PTO-1449

INFORMATION DISCLOSURE CITATION  
IN AN APPLICATION

(Use several sheets if necessary)

Document Number (Optional)

TSMC-02-1147

Application Number

10/719,721

Applicant

Wen-Chi Chien

Filing Date

11/21/03

Group Art Unit

## U. S. PATENT DOCUMENTS

EXAMINER INITIAL	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
	6 5 6 4 1 1 3	5/13/03	Barto et al.	700	99	6/15/01
	6 4 7 0 2 2 7	10/22/02	Rangachari et al.	700	95	12/2/98
	6 2 5 9 9 5 9	7/10/01	Martin	700	99	9/4/98
	6 1 2 8 5 8 8	10/3/00	Chacon	703	6	10/1/97
	5 8 2 6 2 3 8	10/20/98	Chen et al.	705	8	4/2/96
	5 7 6 8 1 3 3	6/16/98	Chen et al.	364	468.01	3/19/96

## FOREIGN PATENT DOCUMENTS

DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	Translation	
					YES	NO

## OTHER DOCUMENTS (Including Author, Title, Date, Portion of Pages, Etc.)

-	"Understanding the Fundamentals of Kanban and Conway Pull Systems Using Simulation", Marek, et al., Proceedings of the 2001 Winter Simulation Conf., pp. 921-929, found on the website www.informs-cs.org, 6/12/03.

EXAMINER

DATE CONSIDERED

EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP § 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to the applicant.